

A New High Intensity Muon Beamline at the Paul Scherrer Institut

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on behalf of the HiMB Project
ETHZ UZH Physics PhD Seminar
11 Sept 2014

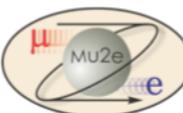
PAUL SCHERRER INSTITUT

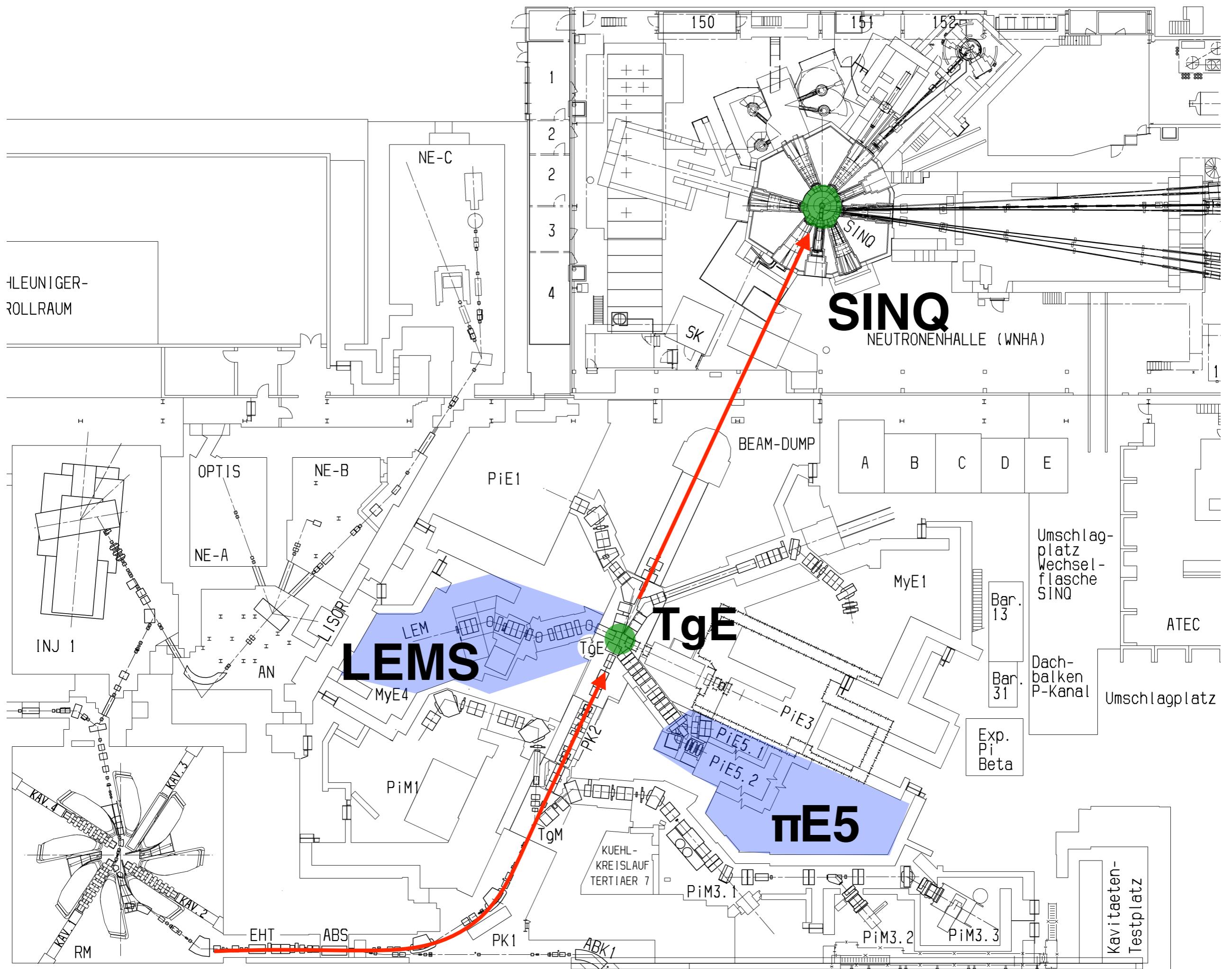


Intensity Frontier Accelerator Facilities

- PSI home to highest intensity DC μ^+ beam @ $10^8 \mu^+/\text{s}$
- New cLFV experiments require significantly higher muon rates to achieve sensitivity goals
MEG: $\mathcal{O}(6 \times 10^{-14})$
Mu3e: $\mathcal{O}(10^{-16})$
- Provide a new μSR facility
- Maintain PSI leadership in high intensity muons
- Potentially: $10^{10} \mu^+/\text{s}$

 **j-PARC** $\rightarrow 10^{10} \mu^-/\text{s}$
COMET: $R_{\mu e} = \mathcal{O}(10^{-17})$

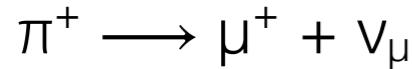
 **Fermilab** $\rightarrow 5 \times 10^{10} \mu^-/\text{s}$
 $R_{\mu e} = \mathcal{O}(10^{-17})$



Pion Production and Surface Muons

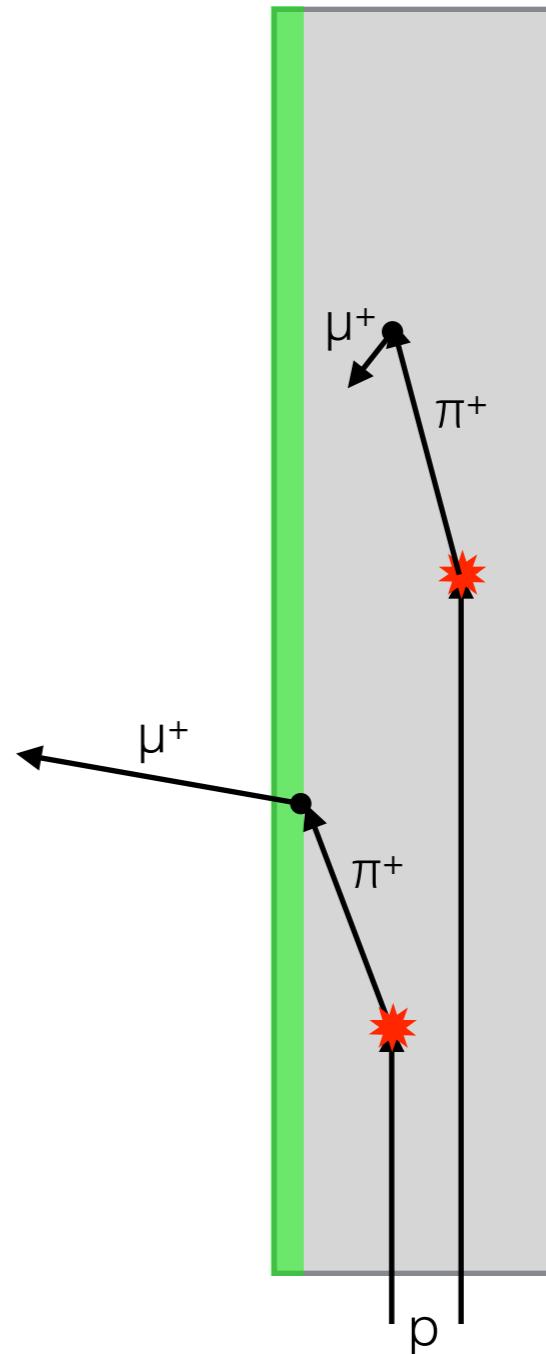
- 590 MeV proton strikes nucleon in target
$$p + p \rightarrow p + n + \pi^+$$
$$p + n \rightarrow n + n + \pi^+$$
$$p + p \rightarrow d + \pi^+$$

- Pion is stopped in the target material and decays.



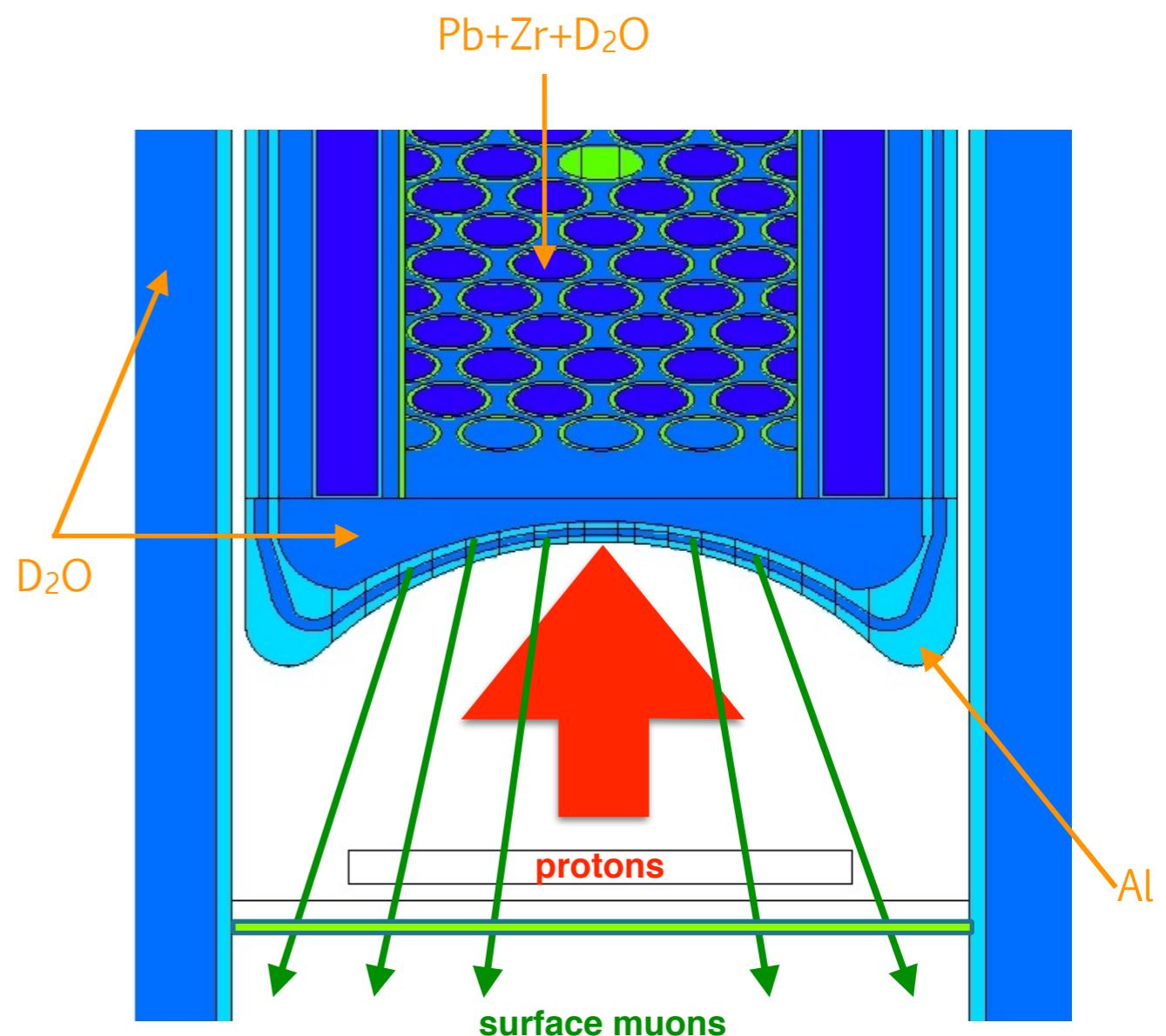
Those near surface of target produce monochromatic “surface muons”.

- $P_\mu = 29.79 \text{ MeV}/c$
 $E_\mu = 4.12 \text{ MeV}$
 $\sim 100\%$ polarized



HiMB Concept

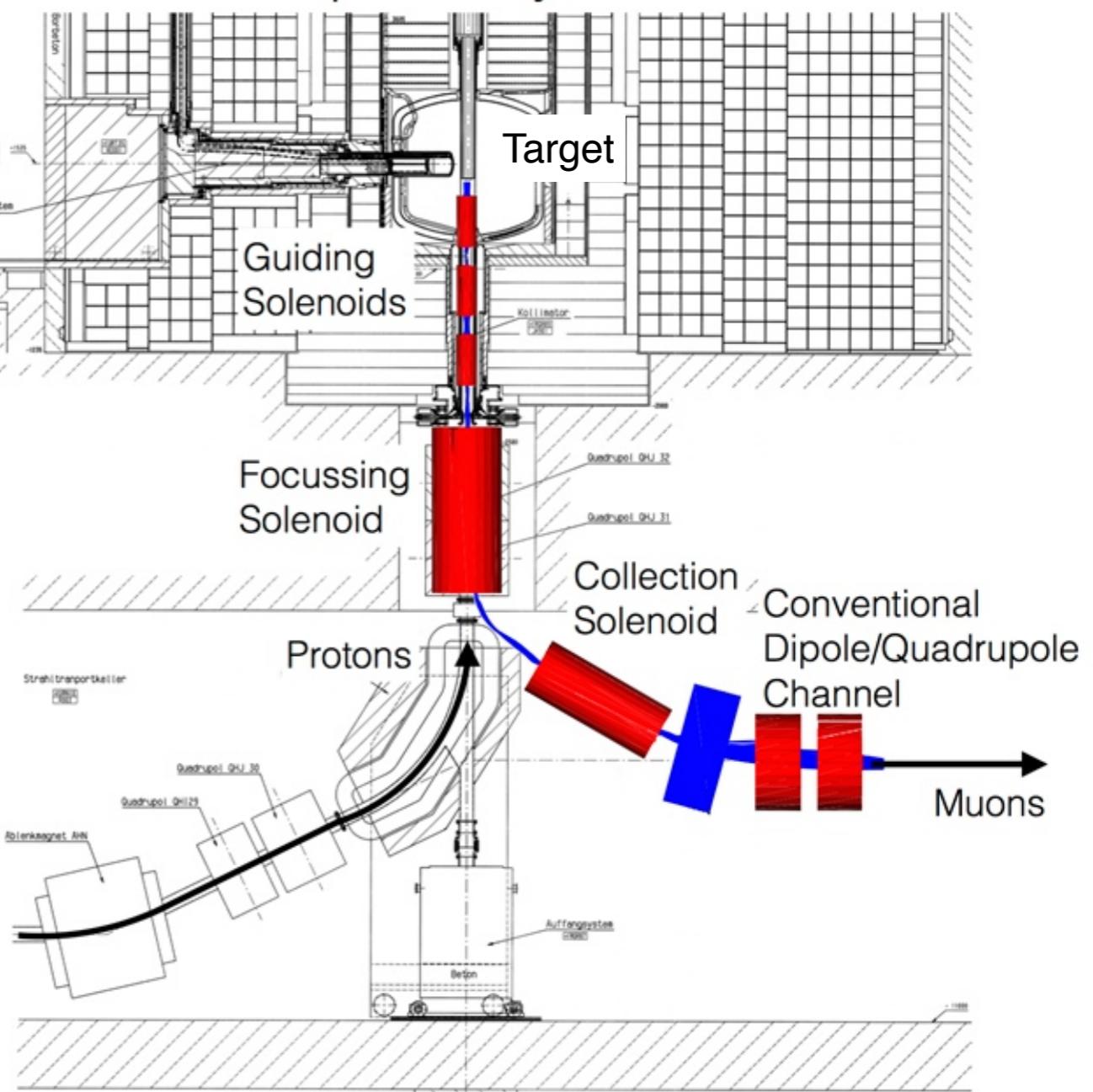
- SINQ spallation neutron source
- Pions produced in SINQ target are stopped in the Al window
- Surface muons that are produced anti-parallel to proton beam are collected



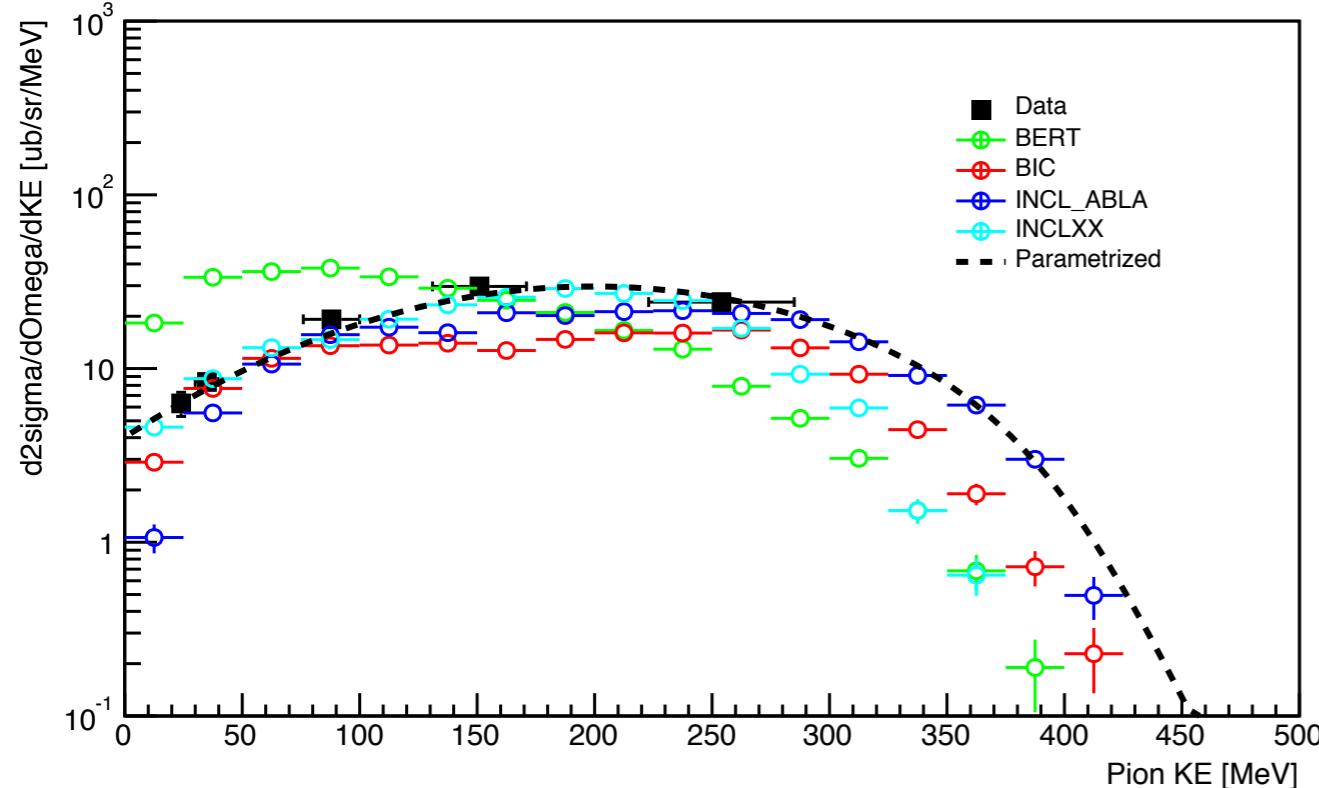
HiMB Concept

- Muons transported opposite to proton beam in solenoid channel. Extracted prior to fringe field of last bending magnet.
- Continue in a conventional beamline to experiment
- Source validation and toolset completed
- Currently studying solenoidal channel acceptance
- $R_{\mu+} = 1.2 \times 10^{11} \mu^+/s$ downward below source with $I_p = 1.7 \text{ mA}$ on SINQ

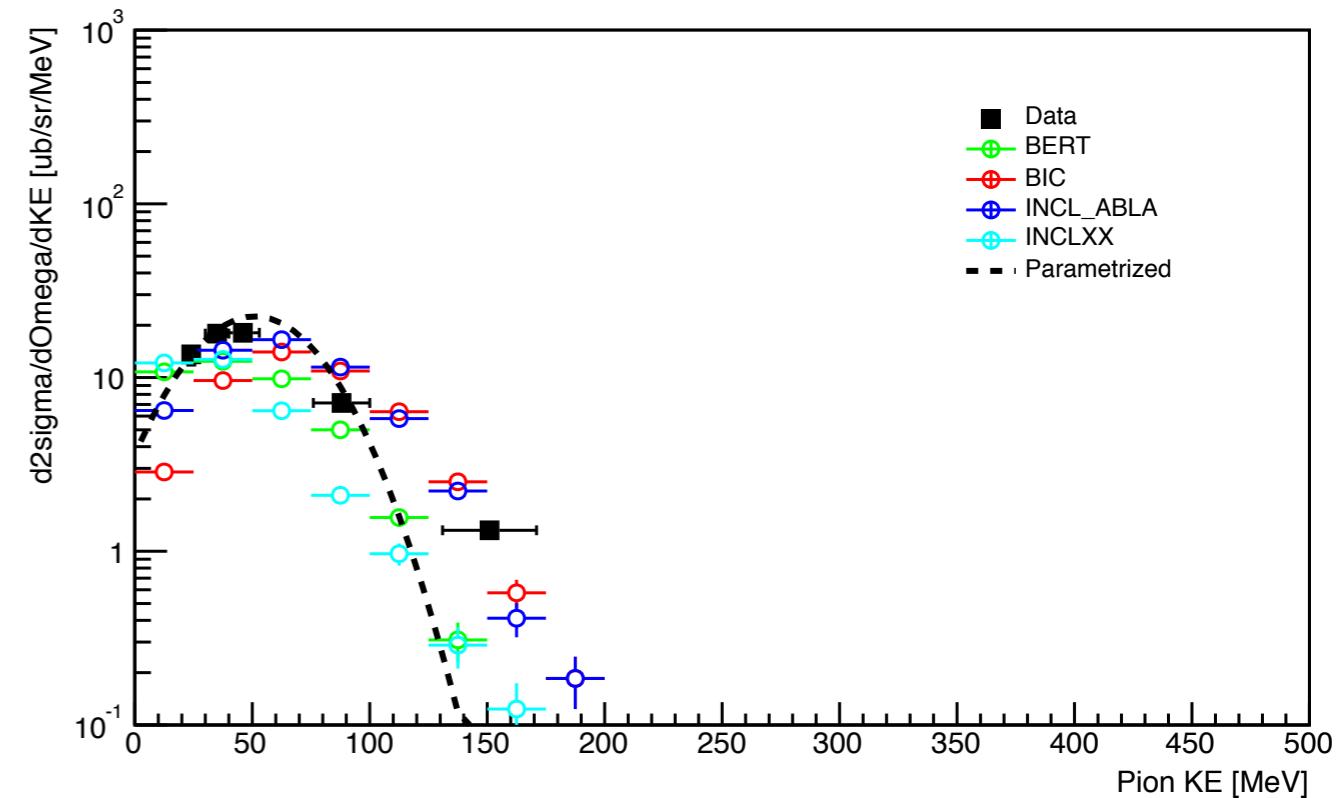
HiMB Conceptual Layout



Cross section on C, 585 MeV, π^+ , $\theta = 22.5^\circ$

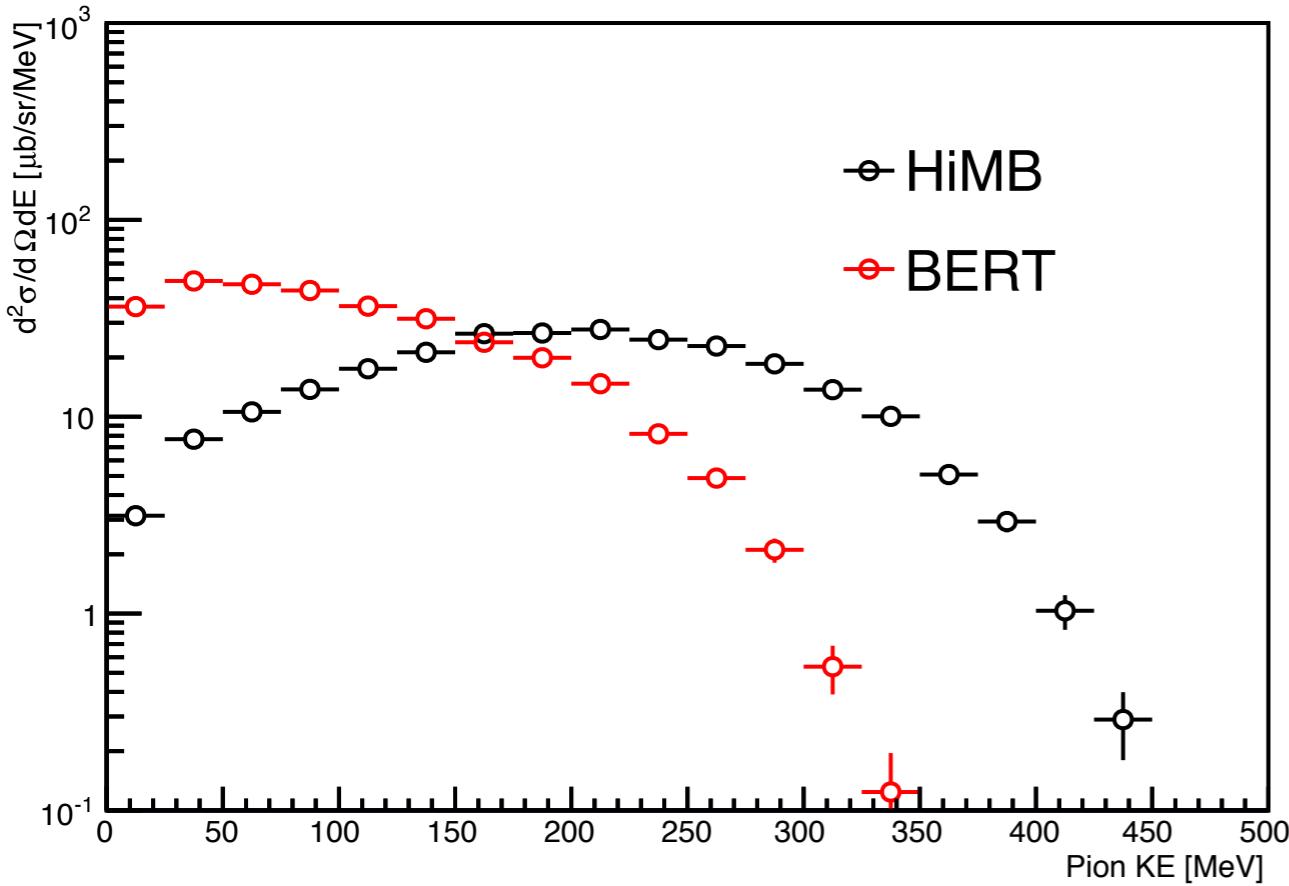


Cross section on C, 585 MeV, π^+ , $\theta = 135^\circ$

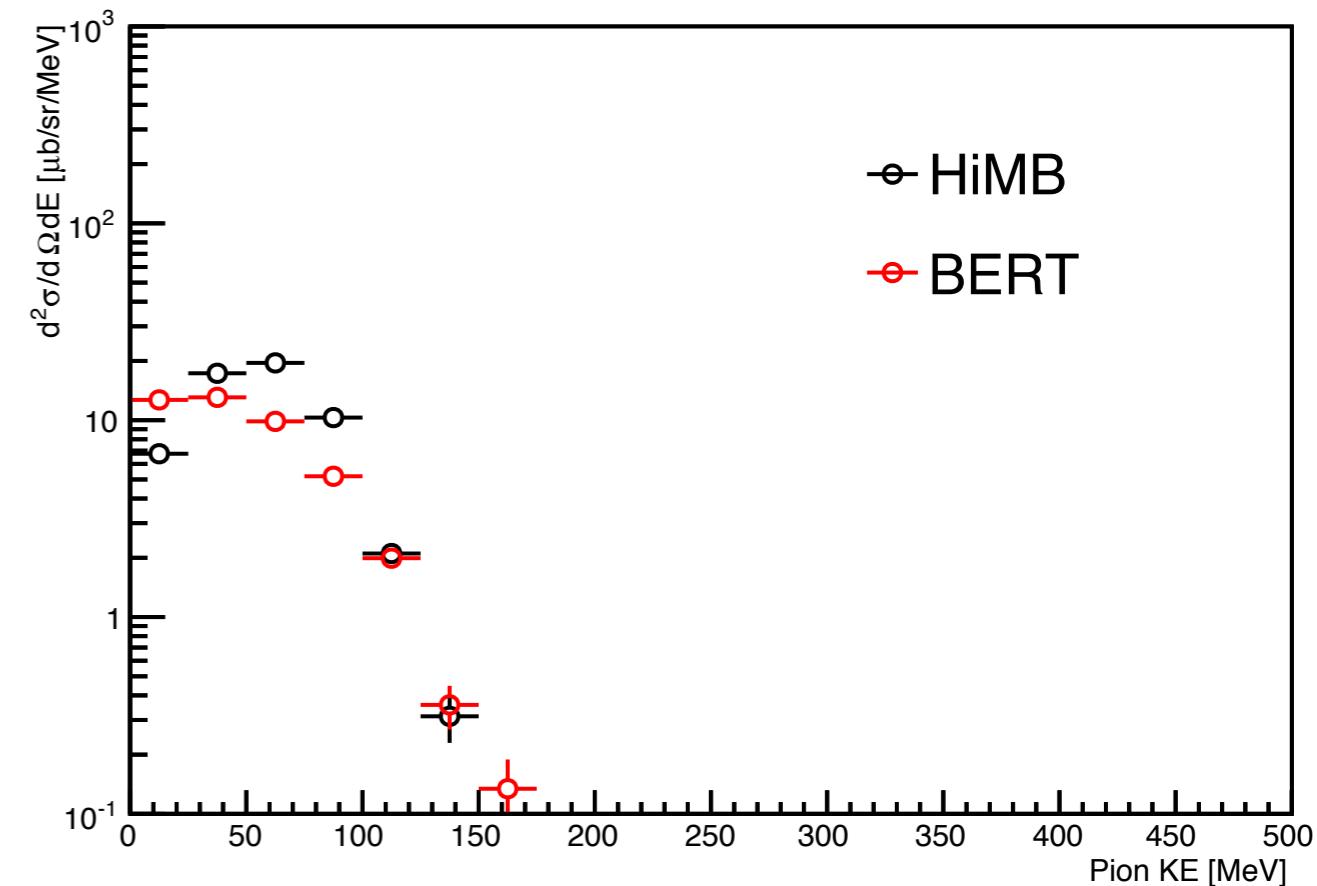


Comparison of Geant4 Models
585 MeV protons on Carbon target

Cross Section π^+ at $\theta = 22.5^\circ$, 585 MeV protons on Target



Cross Section π^+ at $\theta = 135^\circ$, 585 MeV protons on Target



R. L. Burman and E. S. Smith, Los Alamos Tech. Report LA-11502-MS

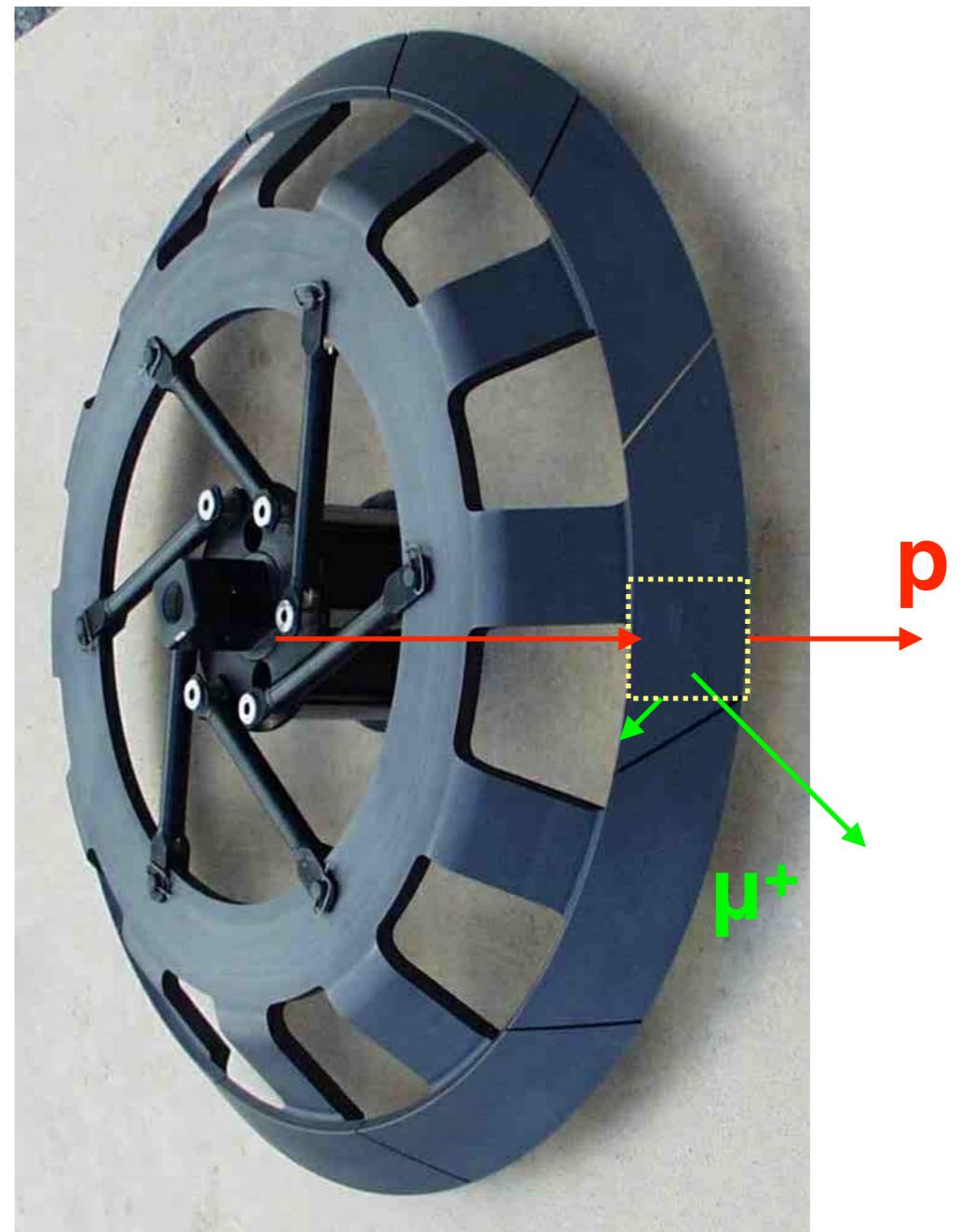
R. Frosch, J. Löfller, and C. Wlgger, PSI Tech. Report TM-11-92-01

HiMB Parameterized Model

Combined parameterization of data collected at PSI and LAMPF, across all production energies and angles

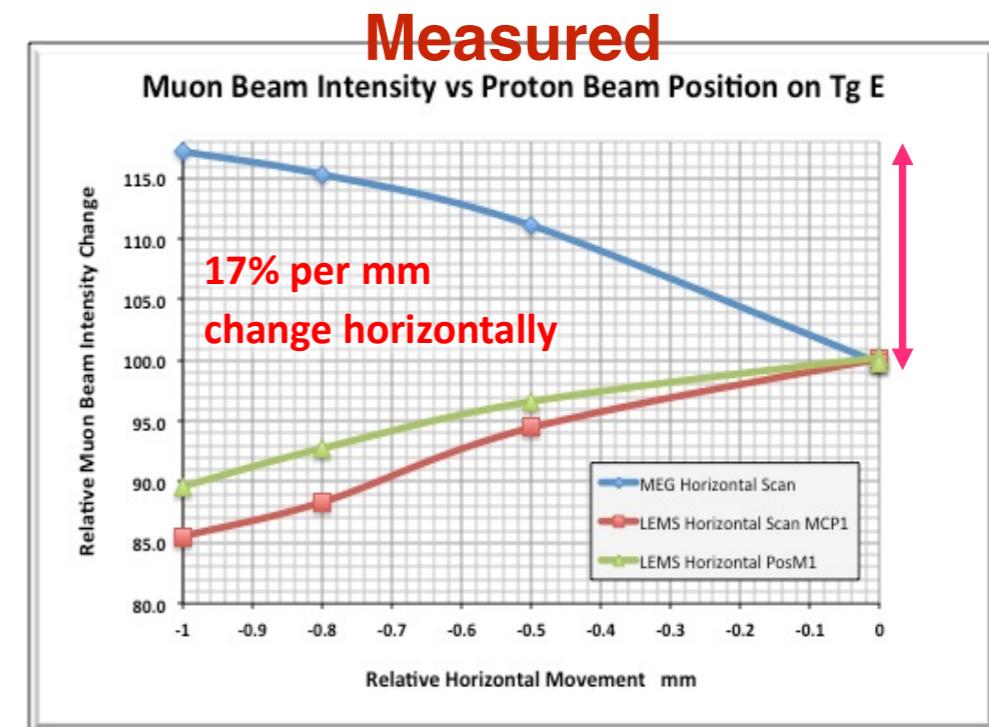
Target E at PSI

- Provides a normalization to HiMB and a validation of sim toolset
- Target E is a graphite truncated hollow cone
 - Approximated as a rectangular section in G4BL
 - Length = 40.0 mm
 - Height = 40.0 mm
 - Width = 6.0 mm



Horizontal Proton Beam Offset

- Horizontal proton beam offset from target center
- Surface muon rate measured simultaneously on opposite sides of TgE
- Higher rates as beam is brought closer to target surface
- HiMB shows better agreement between G4BL and measured rates in LEMS

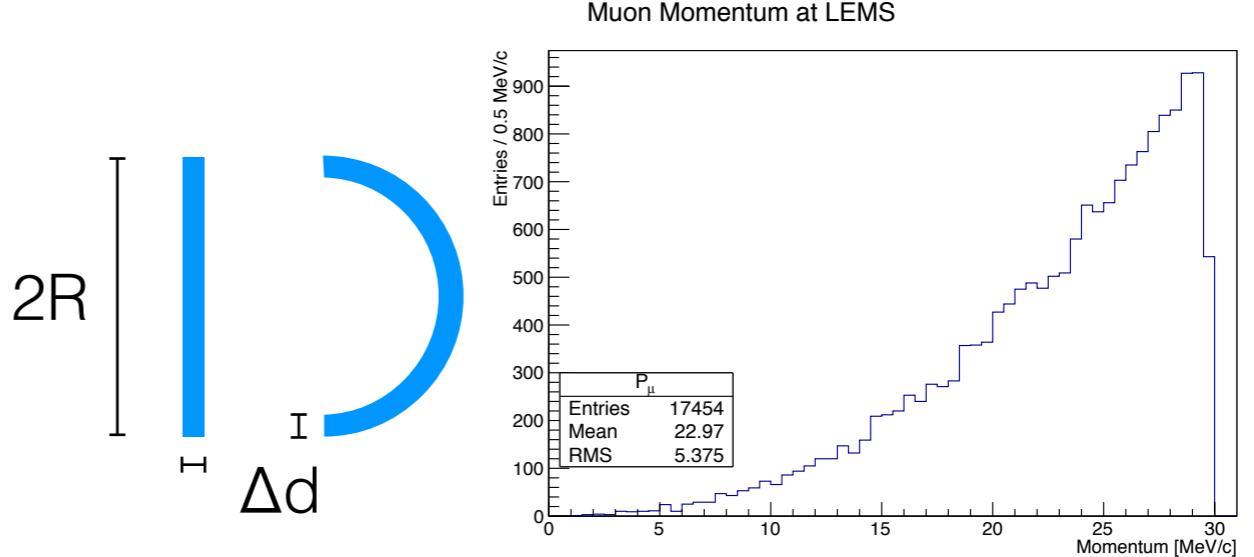


RATIO TO CENTERED BEAM

	LEMS BERT	LEMS HiMB	LEMS Data	PiE5 BERT	PiE5 HiMB	PiE5 Data
0.5 mm	0.87	0.98	0.95	1.12	1.01	1.11
1.0 mm	0.77	0.88	0.87	1.25	1.07	1.17

Radial Grooved Target

- Increasing the surface area/volume should increase the surface muon production
- Grooves along the proton beam direction can provide this increase in surface volume



Groove
Radius
[mm]

1.0

1.5

2.0

Enhancement Ratio

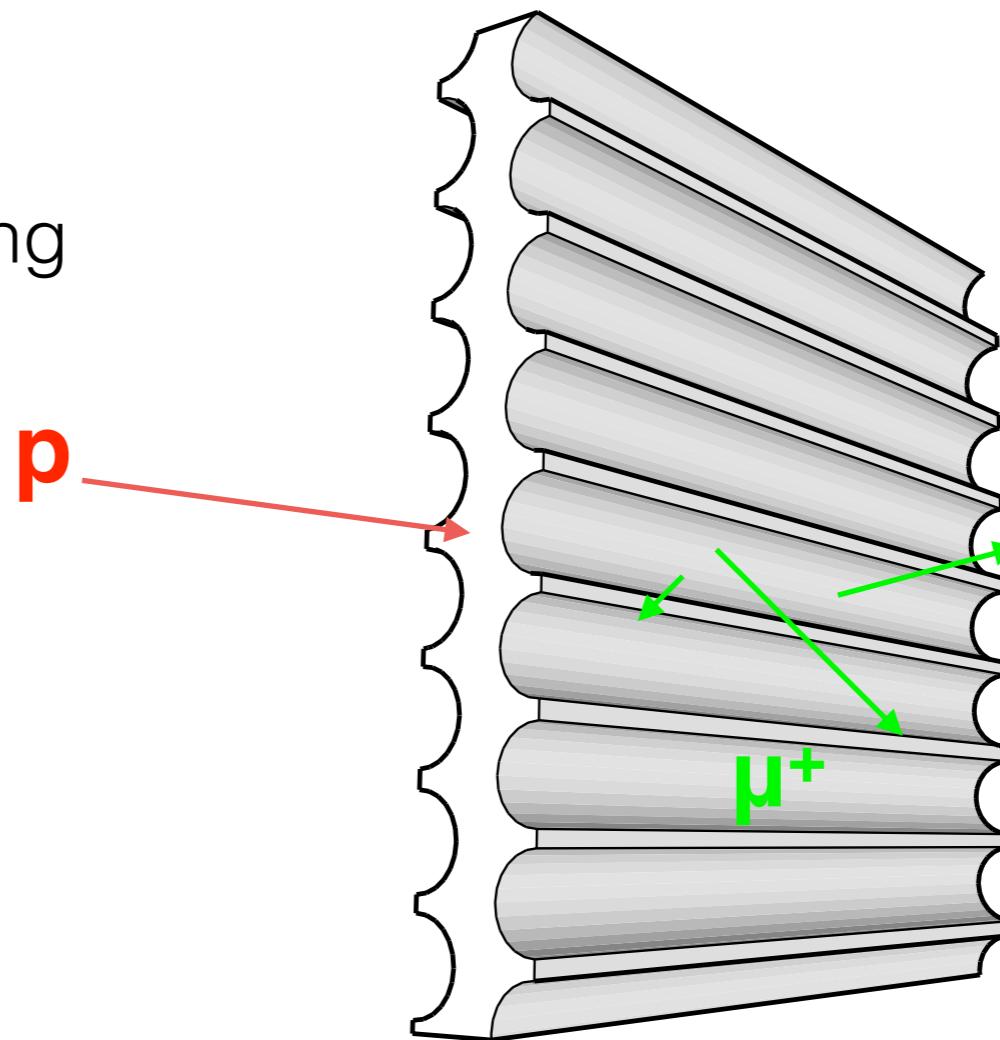
1.35

1.40

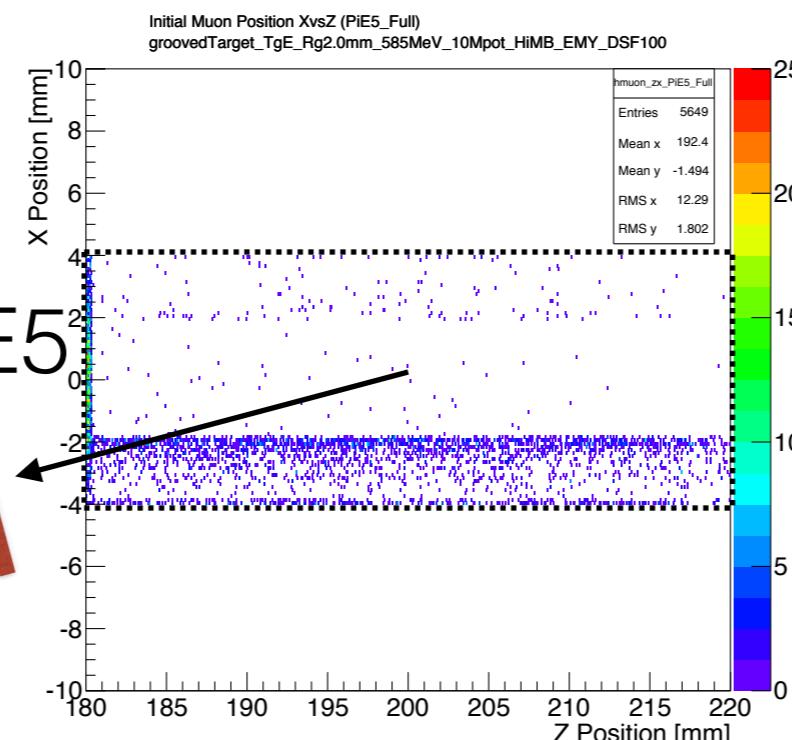
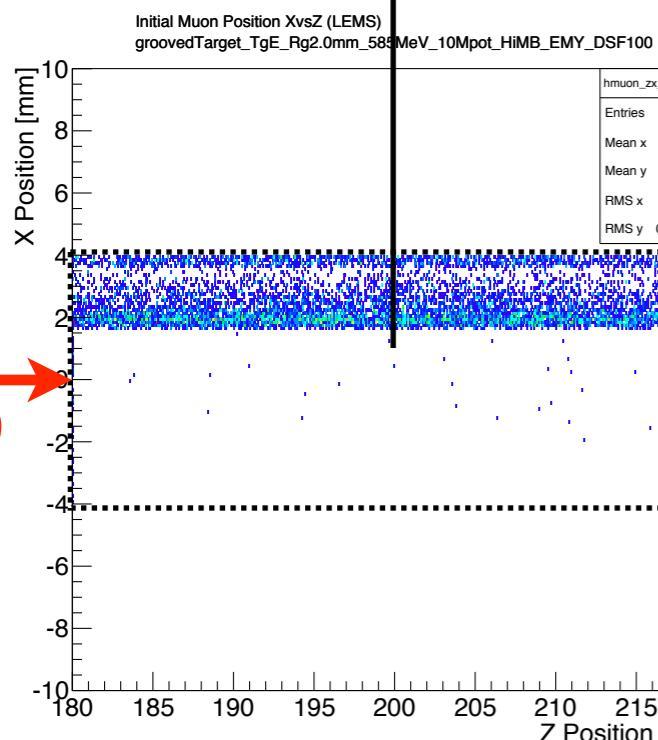
1.45

Radial Grooved Target

- Alternate design for increasing surface muon production
- Grooves are staggered to maintain a standard target width
 - Width = $6.0 \text{ mm} + R_g$



LEMS



Ratio to Standard

Groove Radius [mm]	LEMS	PiE5
1.0	1.02	0.99
1.5	1.02	1.02
2.0	1.04	0.99

Groove Radius [mm]	LEMS	PiE5
1.0	1.02	0.99
1.5	1.02	1.02
2.0	1.04	0.99

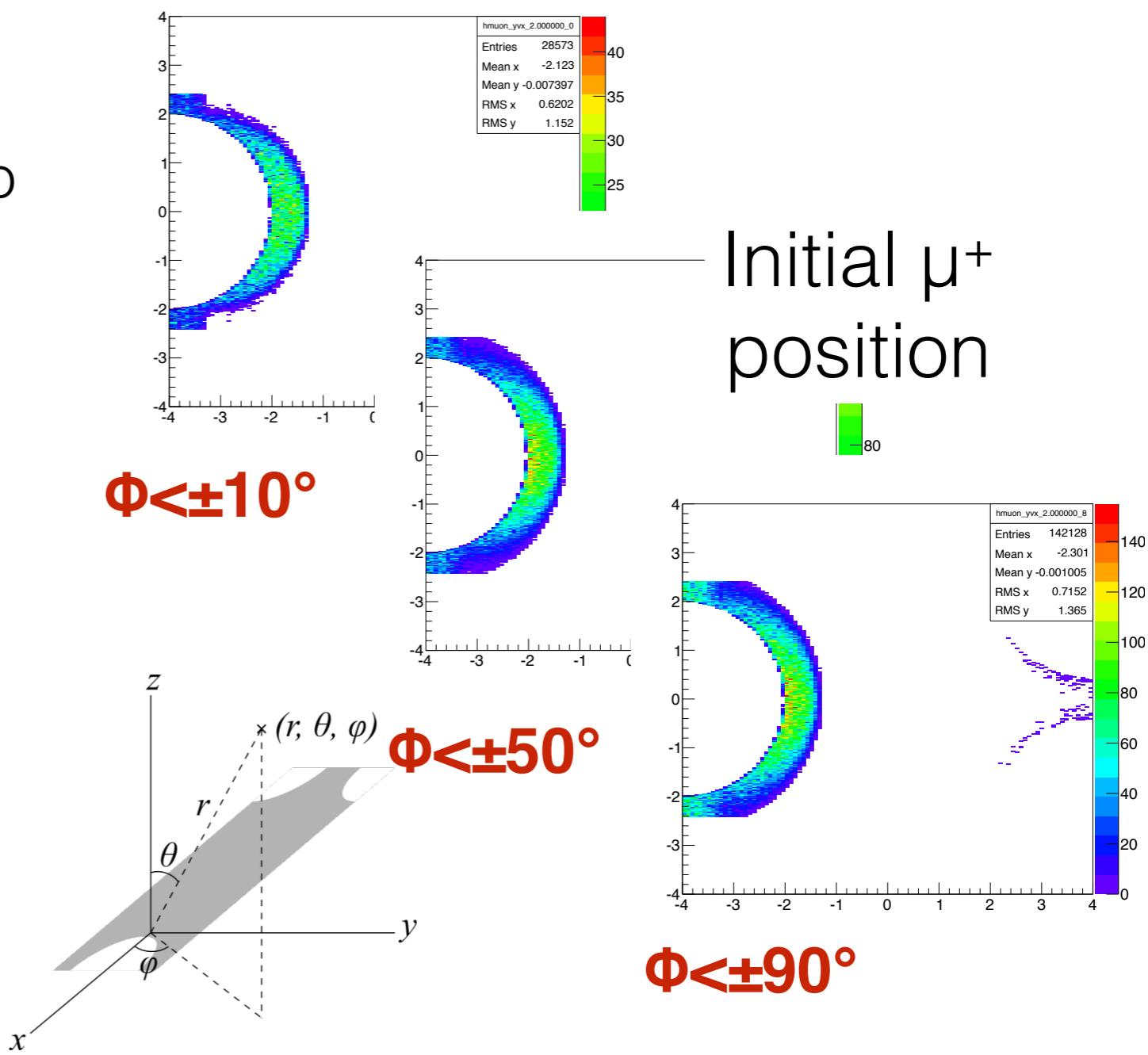
Grooved Targets

Approximately 4% enhancement for 2.0 mm groove configuration

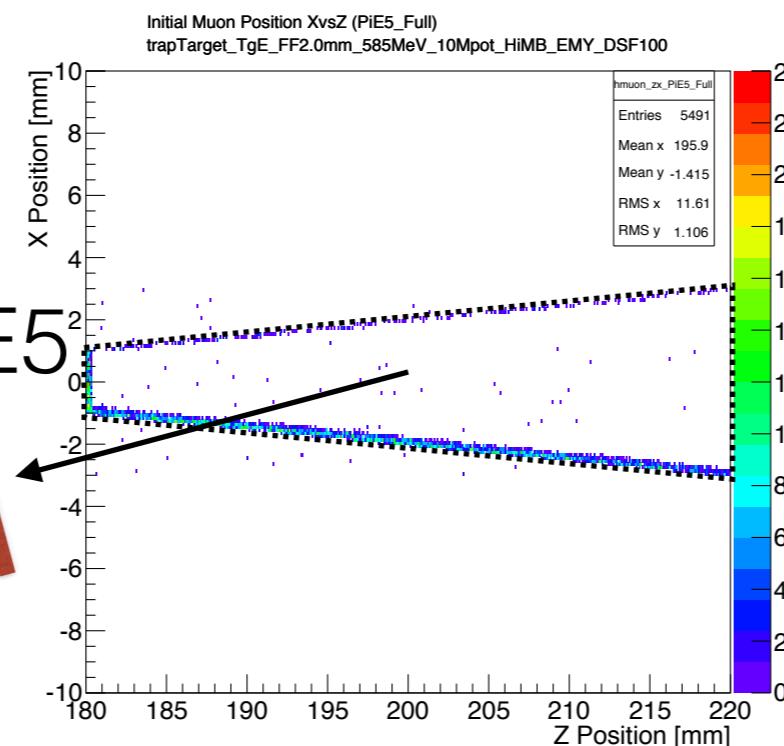
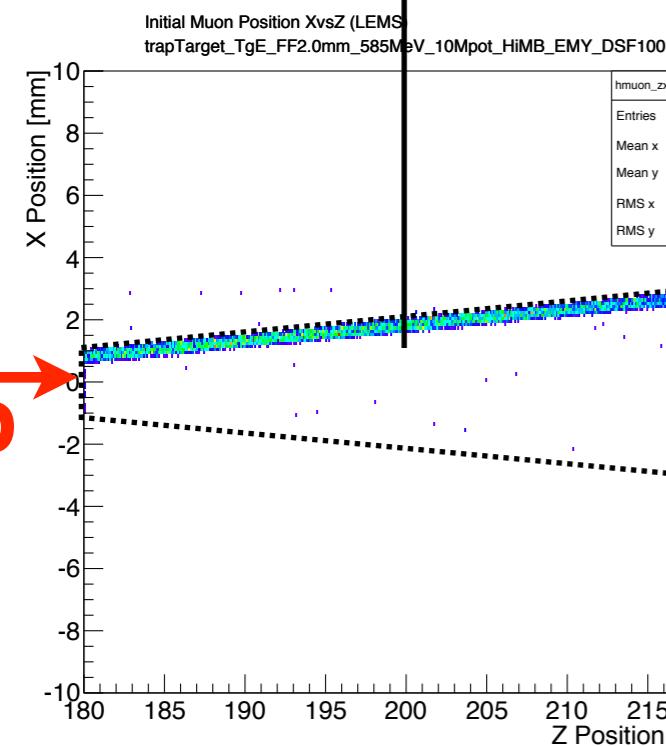
Acceptance Depth

- The acceptance depth in a groove is at the maximum where the groove is closest to the target center
- This depth tapers near the max target width

- Has a crescent shape for small acceptance angles (realistic for beamlines)
- Not the full surface volume expected



LEMS



Ratio to Standard

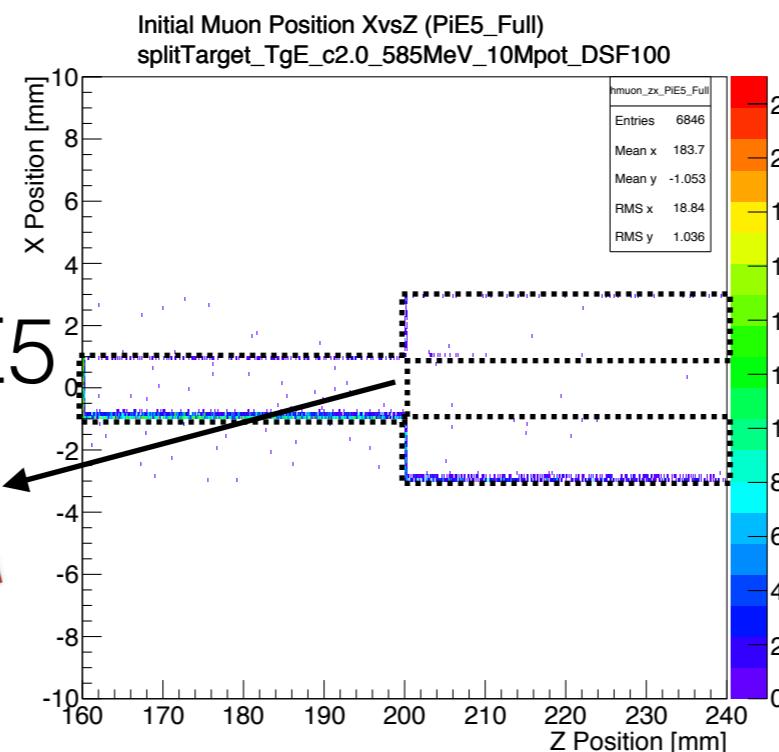
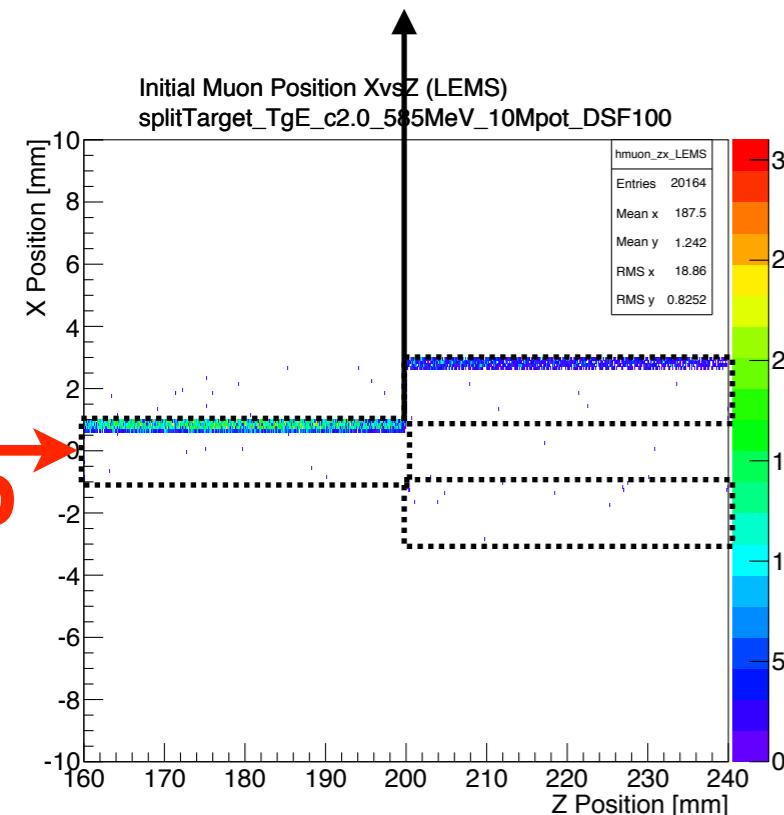
Front Face LEMS PiE5
Width [mm]

4.0	1.08	1.00
3.0	1.08	1.02
2.0	1.13	0.96

Trapezoidal Target

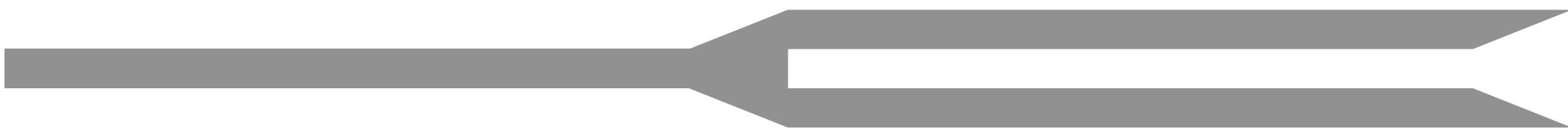
Approximately 13% enhancement for 2.0 mm front face target configuration

LEMS



Ratio to Standard

Center Width [mm]	LEMS	PiE5
4.0	1.27	1.20
3.0	1.35	1.20
2.0	1.48	1.20



Fork Target

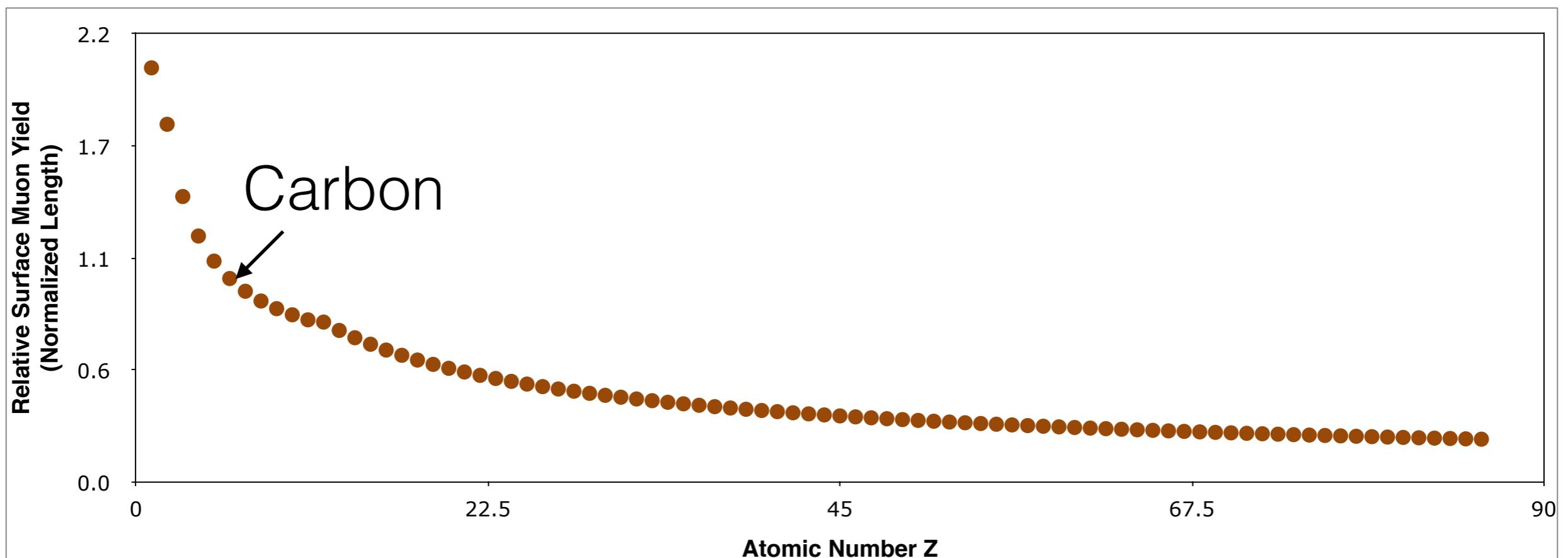
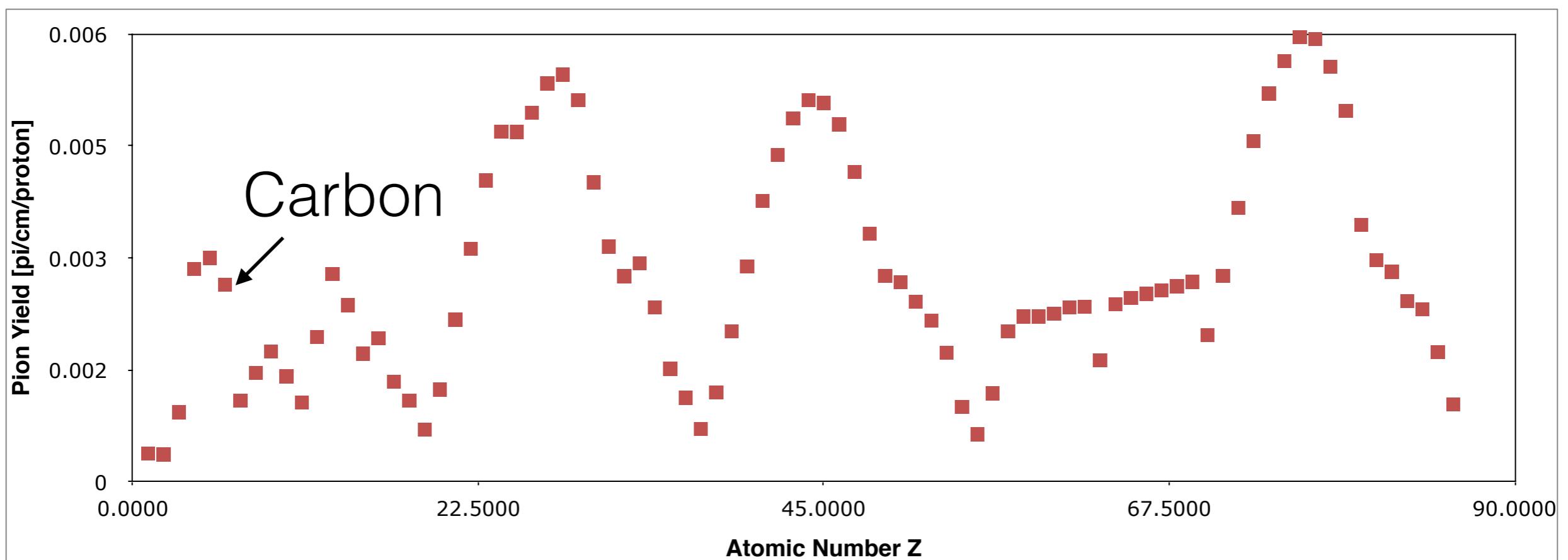
Approximately 50% enhancement for 2.0 mm center target width configuration

Alternate Materials

- Search for high pion yield materials → higher muon yield

$$\text{relative } \mu^+ \text{ yield} \propto \pi^+ \text{stop density} \cdot \mu^+ \text{Range} \cdot \text{length}$$

$$\begin{aligned} &\propto n \cdot \sigma_{\pi^+} \cdot SP_{\pi^+} \cdot \frac{1}{SP_{\mu^+}} \cdot \frac{\rho_C(6/12)_C}{\rho_x(Z/A)_x} \\ &\propto Z^{1/3} \cdot Z \cdot \frac{1}{Z} \cdot \frac{1}{Z} \\ &\propto \frac{1}{Z^{2/3}} \end{aligned}$$



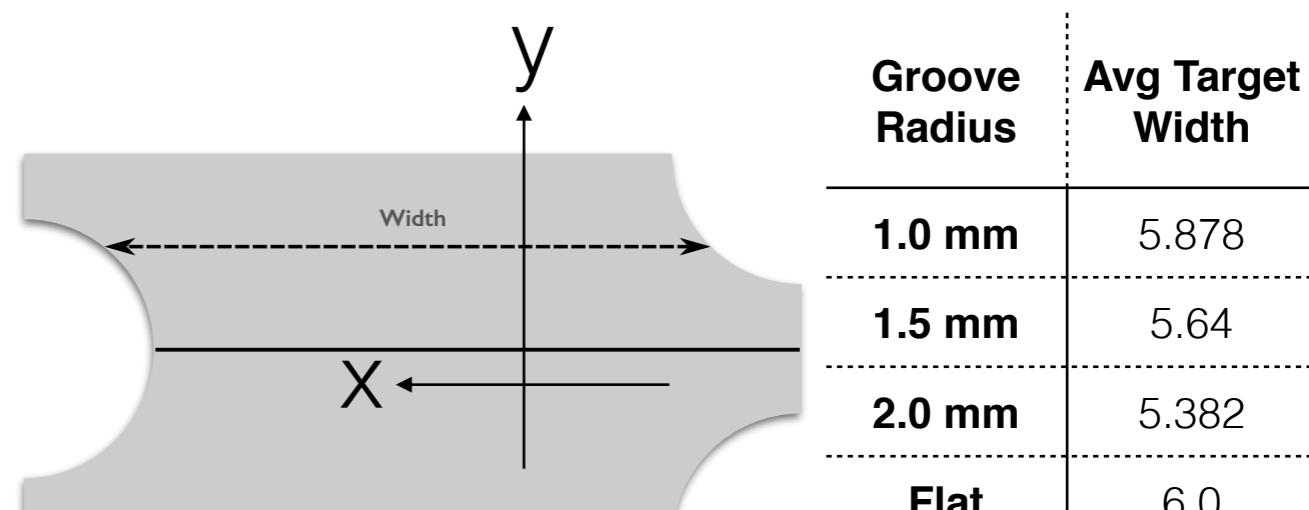
Conclusions

- HiMB project in 2-year feasibility study
 - Muon rate: 1×10^{11} μ/s from source downward
 - Currently evaluating solenoidal collection
- Parameterized π^+ cross section implemented
- Target E used as validation of G4BL
 - Possible improvements to TgE leading to higher muon rates

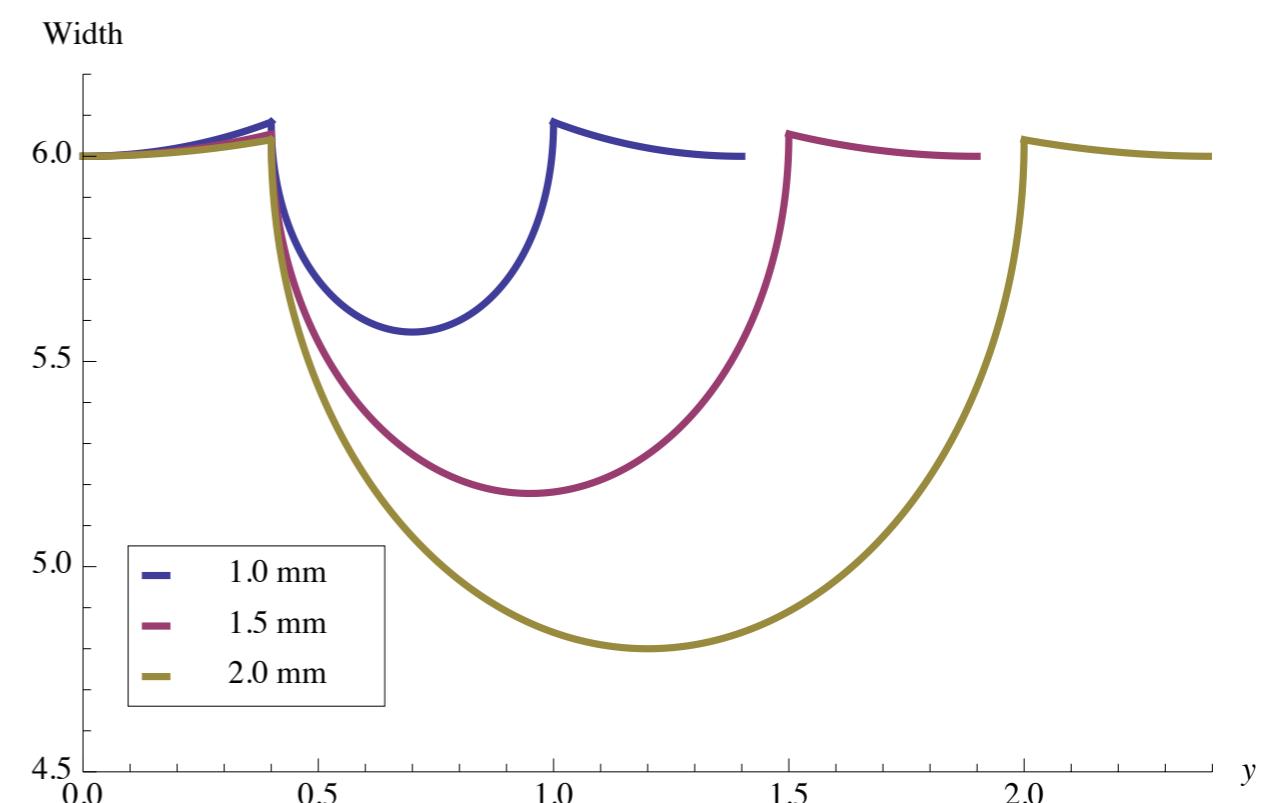
Backup Slides

Target Width

- The Target width (x-axis) varies along the y-axis
- This creates an effective width of the target that is less than the standard 6.0 mm



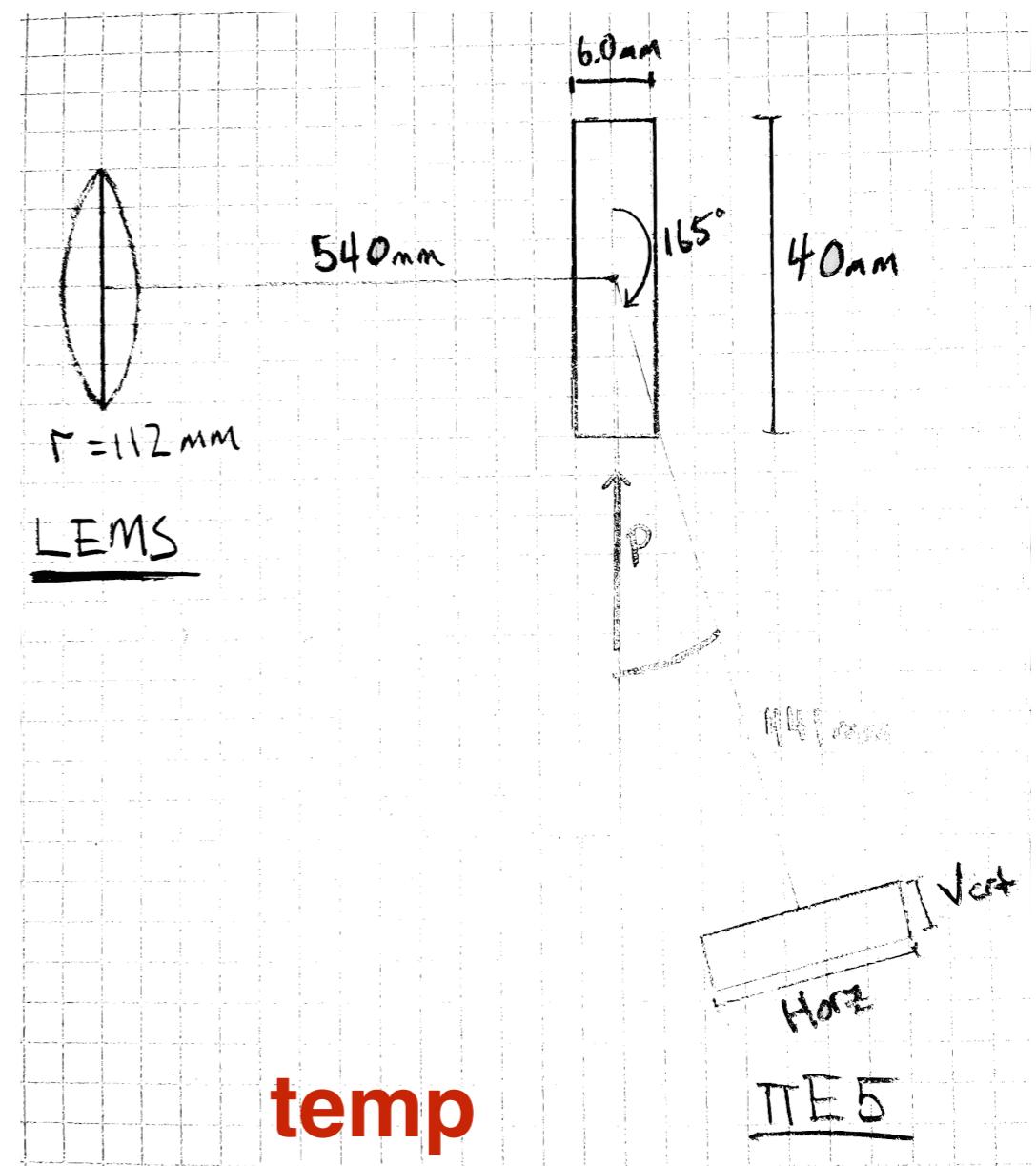
Groove Radius	Avg Target Width
1.0 mm	5.878
1.5 mm	5.64
2.0 mm	5.382
Flat	6.0



Detector Dimensions

- LEMS:
 - 540 mm from c.o.t.
 - $r = 112 \text{ mm}$
- PiE5_Full:

- 441 mm from c.o.t.
- $v = 79 \text{ mm}$, $h = 353 \text{ mm}$



PARAMETERIZATION OF PION PRODUCTION
AND REACTION CROSS SECTIONS
AT LAMPF Energies

by

R. L. Burman and E. S. Smith

ABSTRACT

A parameterization of pion production and reaction cross sections is developed for eventual use in modeling neutrino production by protons in a beam stop. Emphasis is placed upon smooth parameterizations for proton energies up to 800 MeV, for all pion energies and angles, and for a wide range of materials. The resulting representations of the data are well-behaved and can be used for extrapolation to regions where there are no measurements.

Inclusive π^+ Production from Carbon ($T_p = 585\text{MeV}$)

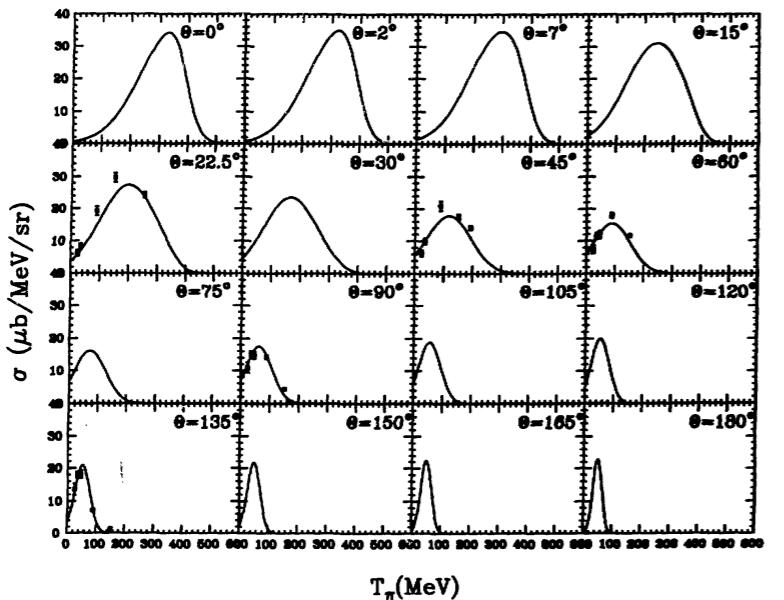


Fig. 7. The parameterization for π^+ production from carbon is compared with the data from Ref. 4.

PSI	PAUL SCHERRER INSTITUT	Registrierung TM-11-92-01
	Labor für Kern- und Teilchenphysik	
Titel	Decay of pions trapped in graphite	Ersetzt —
Autor / en	R. Frosch, J. Löffler, C. Wigger	Erstellt 27.10.1992/FR11

ARCHIVEXEMPLAR 1

Unausleihbar?

Abstract

This report is concerned with calculations needed for the analysis of the $p_\mu A$ experiment, in which the momentum of muons from the decay $\pi^+ \rightarrow \mu^+ \nu_\mu$ of stopped pions is measured in an 'Arizona' surface muon beam. The experimental muon spectra are consistent with the assumption that the pions stopped in the graphite production target are trapped in a potential well of the form $V(r) = V_0 + \frac{1}{2}k_s r^2$, with $k_s \approx 1.0 \cdot 10^{17} \text{ eV/cm}^2$. This potential well agrees with that recently derived by Y. Shirasu et al. for hydrogen and deuterium atoms dissolved in graphite.

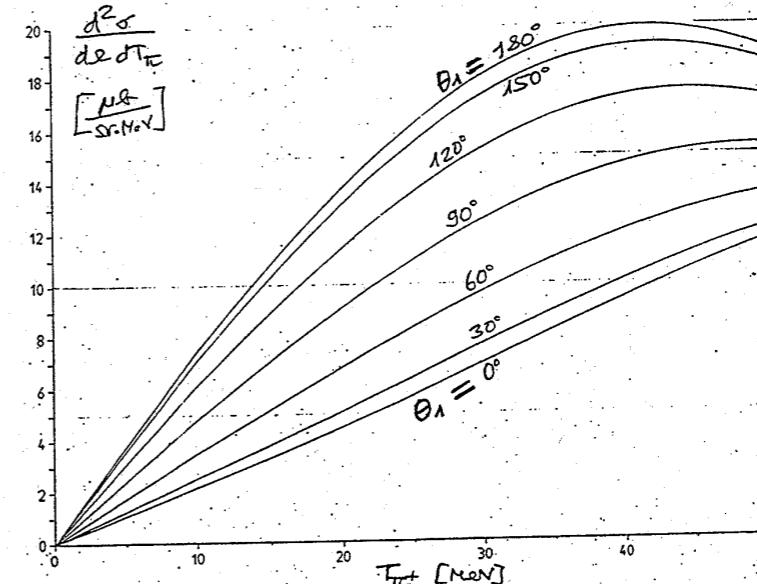
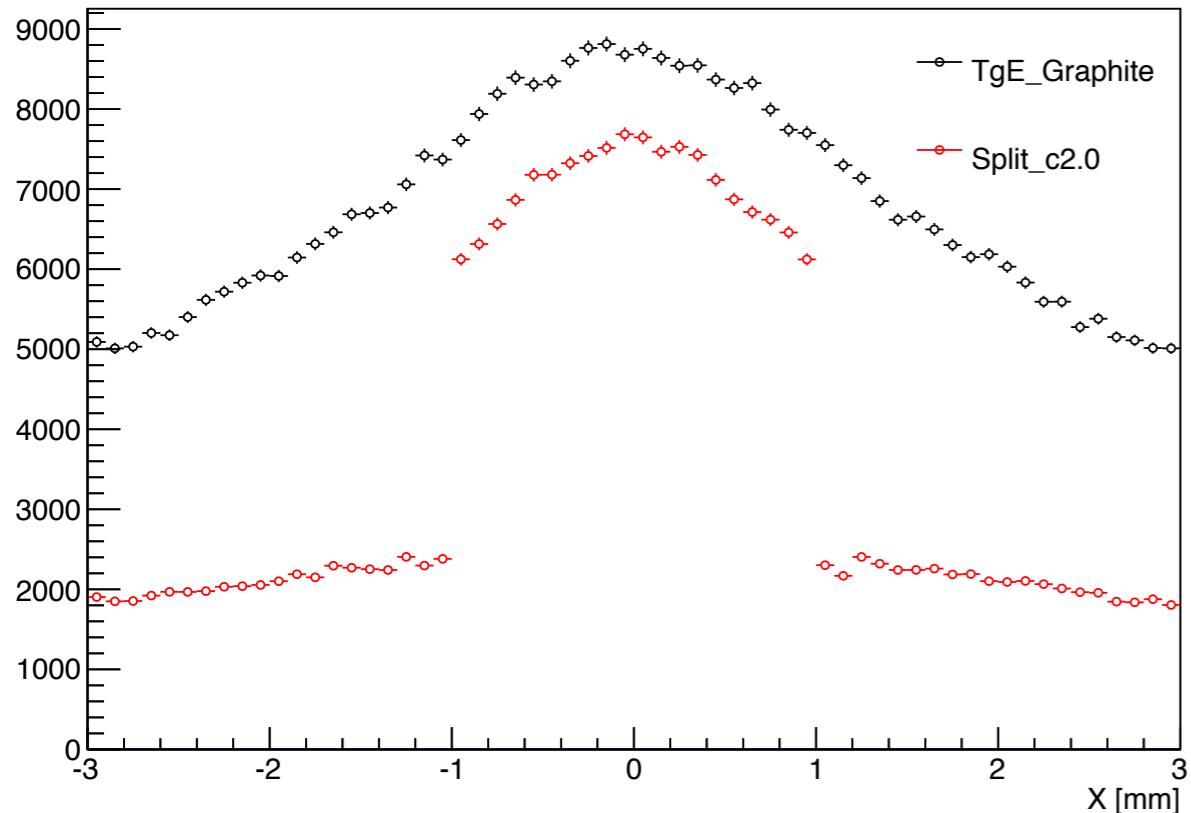


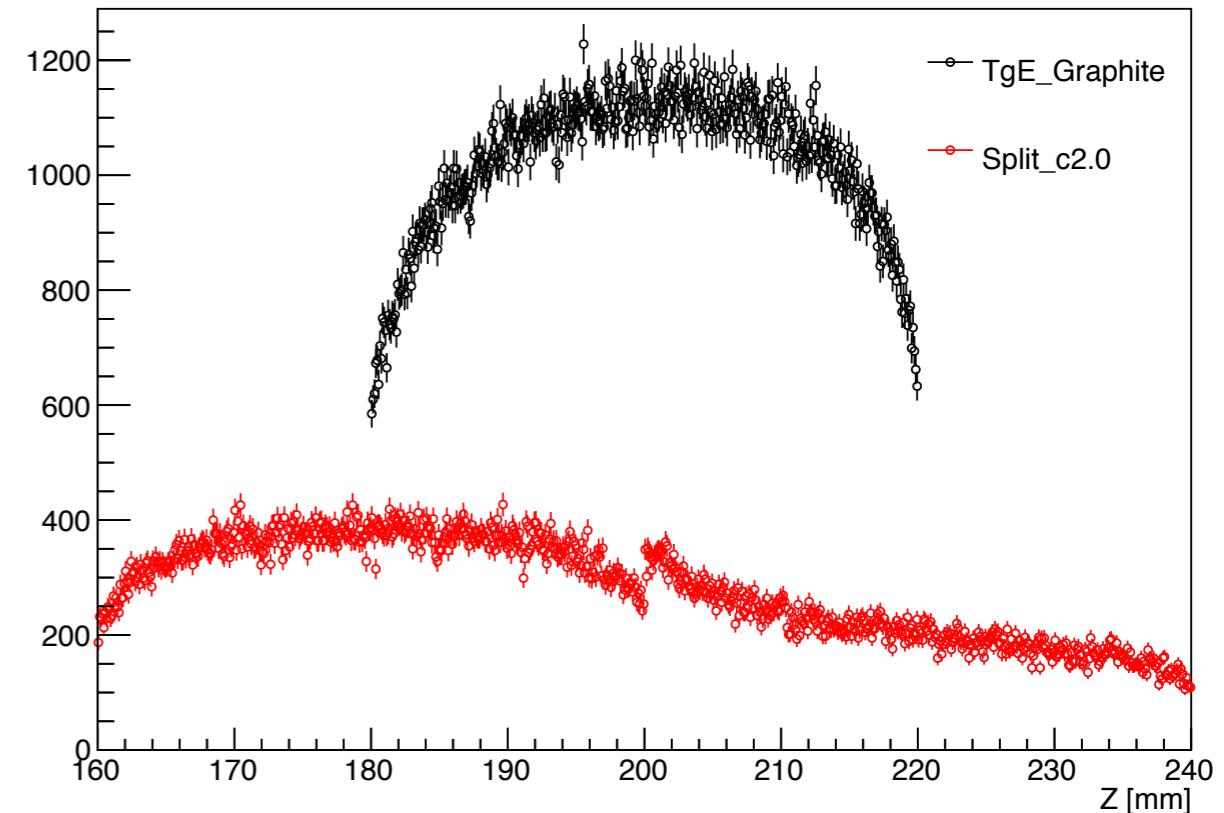
Figure 10: Differential π^+ -production cross-sections according to Eq. (31), for 580MeV-protons in ^{12}C . T_{π^+} : laboratory kinetic energy of produced π^+ ; Θ_1 : laboratory angle between proton and pion momentum vectors.

Pion production parameterization

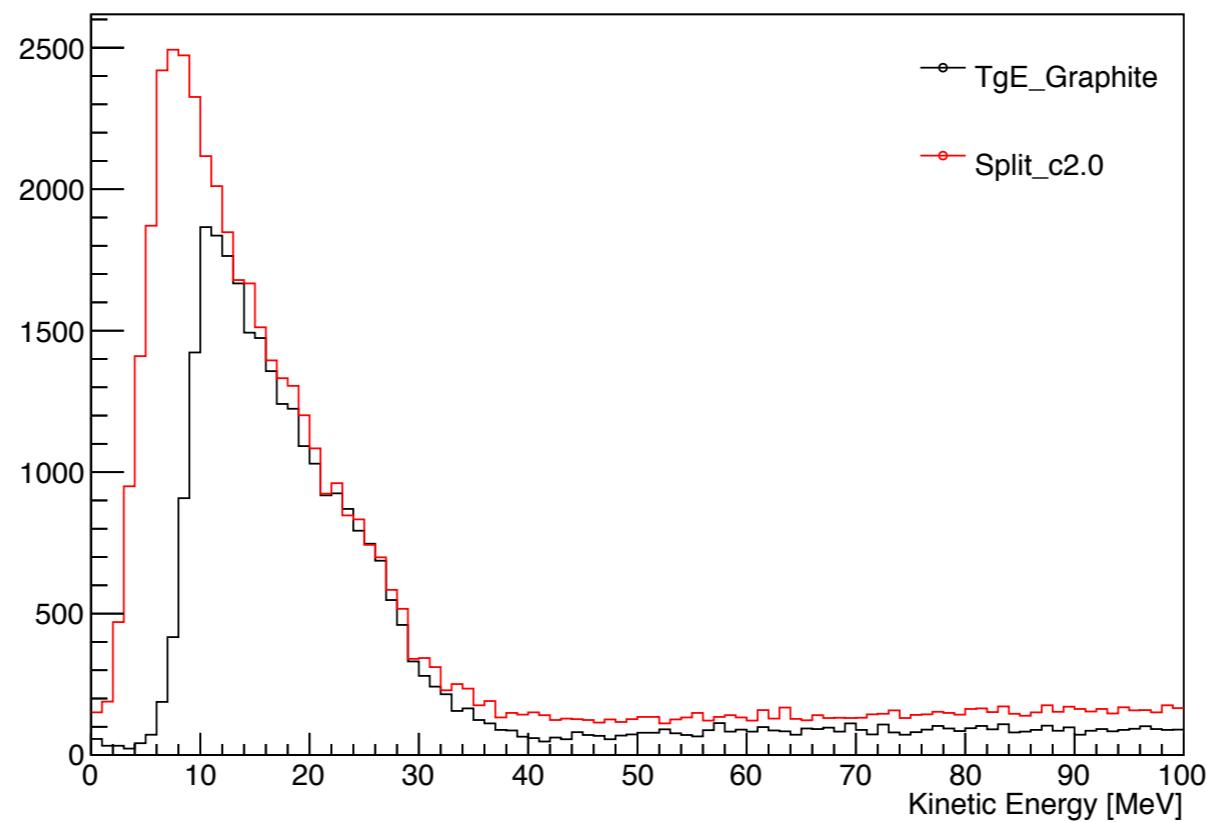
Pion Stop Distribution - X



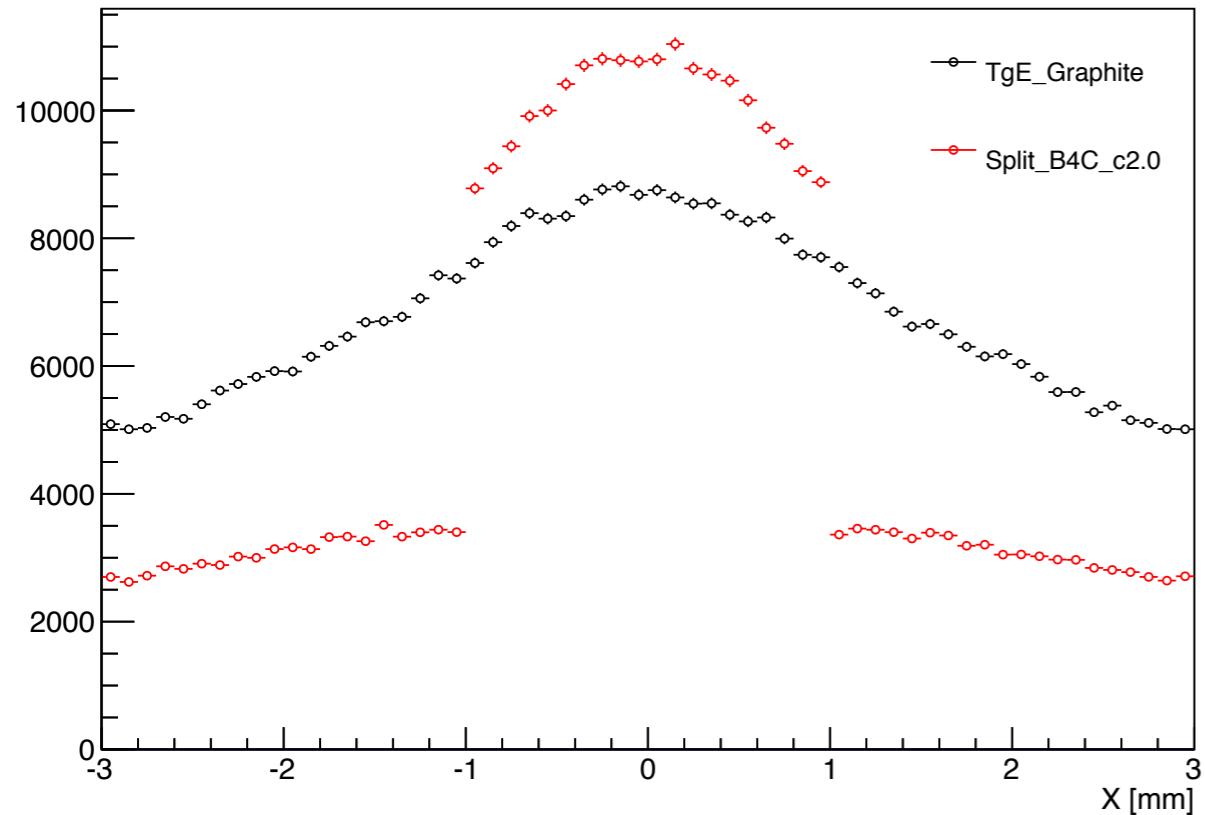
Pion Stop Distribution - Z



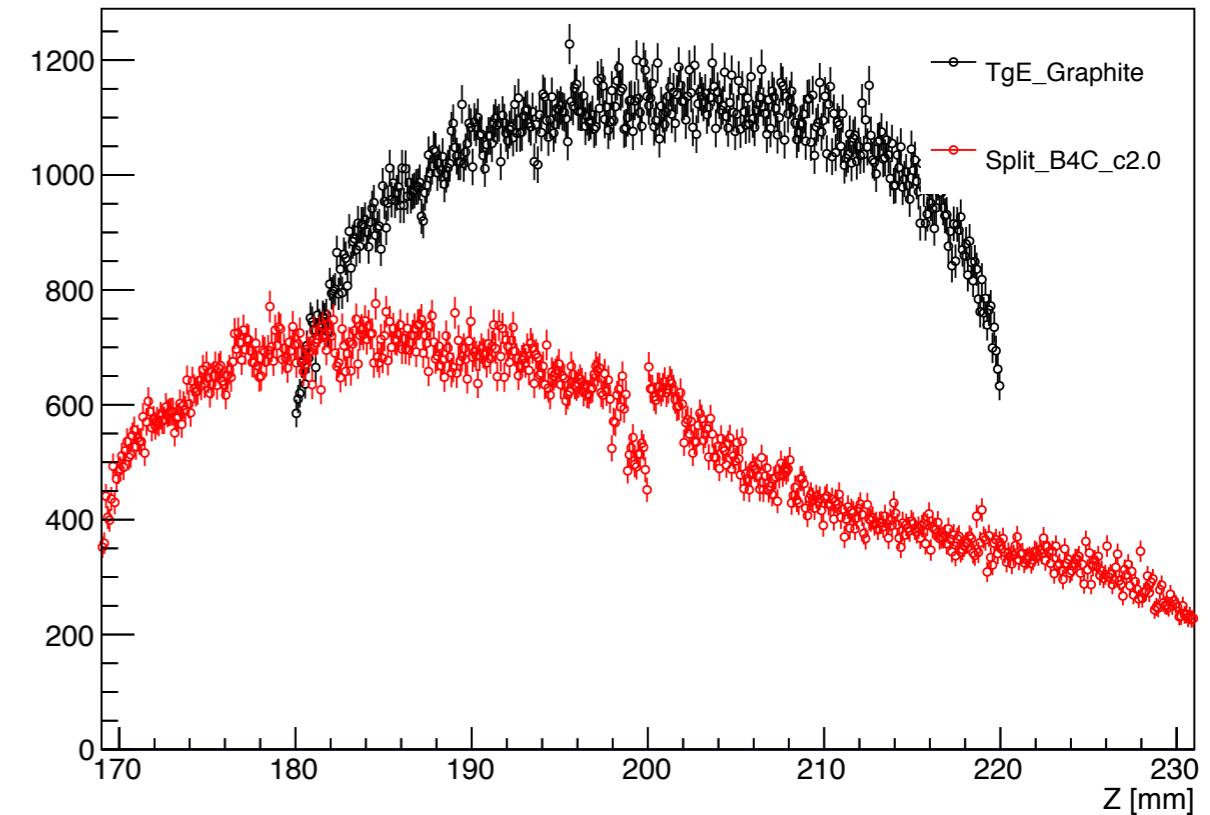
Pion Initial KE - In Surface



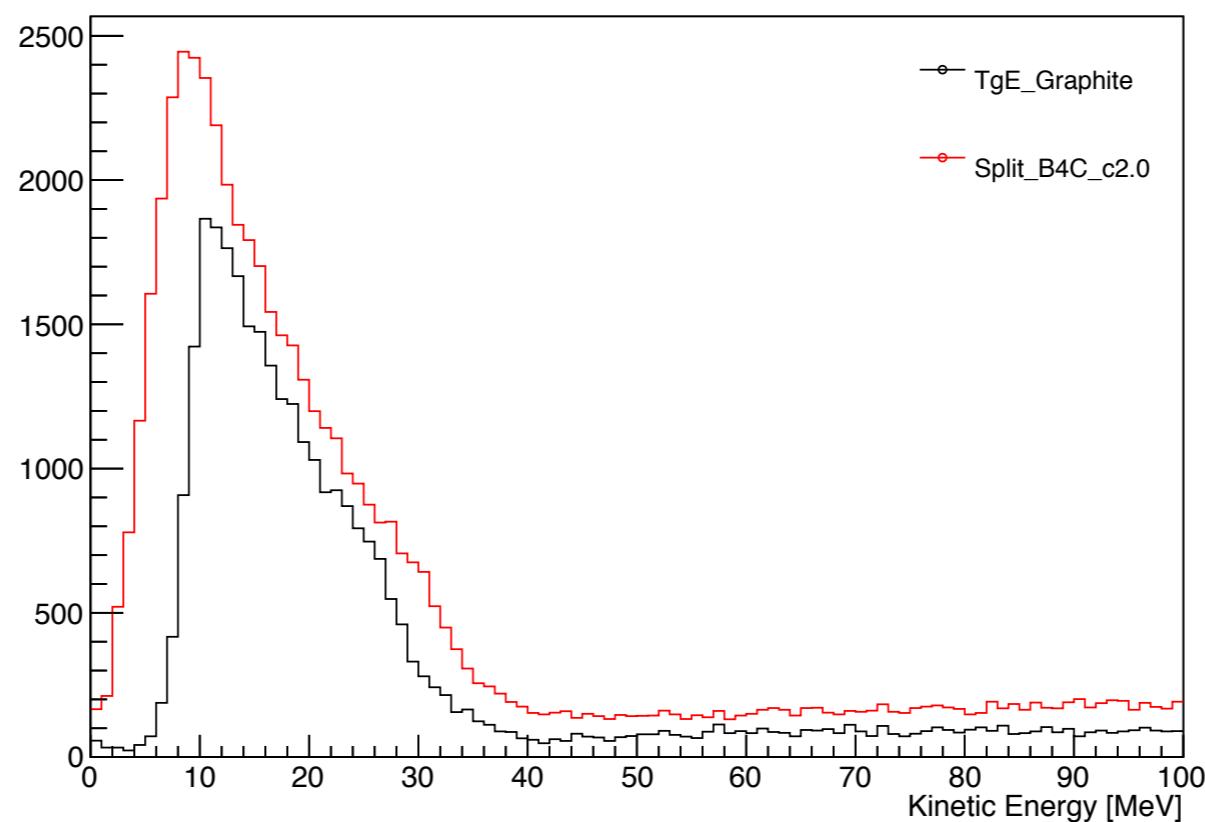
Pion Stop Distribution - X



Pion Stop Distribution - Z



Pion Initial KE - In Surface



LEMS

PIE5

17780 Tg E
AHSW 41
FSH 41
FS 42

Tg E

QHTC 18
MHP-MHS 31/32

ASR 61
WSX 61-62